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AMENDMENT TRANSMITTAL LETTER				Docket No. SON-2920	
Application No.	Filing Date	Examiner	Art Unit		
10/780,667-Conf. #1986	February 19, 2004	Christopher G. Young	1756		
Applicant(s): Ichiro HASE					
Invention: EXPOSURE PATTERN OR MASK AND INSPECTION METHOD AND MANUFACTURE METHOD FOR THE SAME					
TO THE COMMISSIONER FOR PATENTS					
Transmitted herewith is an amendment in the above-identified application. The fee has been calculated and is transmitted as shown below.					
CLAIMS AS AMENDED					
	Claims Remaining After Amendment	Highest Number Previously Paid	Number Extra Claims Present	Rate	
Total Claims	15	23 =		x	0.00
Independent Claims	2	- 3 =		x	0.00
Multiple Dependent Claims (check if applicable) <input type="checkbox"/>					
Other fee (please specify):					
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT:					0.00
<input checked="" type="checkbox"/> Large Entity <input type="checkbox"/> Small Entity					
<input checked="" type="checkbox"/> No additional fee is required for this amendment.					
<input type="checkbox"/> Please charge Deposit Account No. _____ in the amount of \$ 0.00 . A duplicate copy of this sheet is enclosed.					
<input type="checkbox"/> A check in the amount of \$ _____ to cover the filing fee is enclosed.					
<input type="checkbox"/> Payment by credit card. Form PTO-2038 is attached.					
<input checked="" type="checkbox"/> The Director is hereby authorized to charge and credit Deposit Account No. 18-0013 as described below. A duplicate copy of this sheet is enclosed.					
<input checked="" type="checkbox"/> Credit any overpayment.					
<input checked="" type="checkbox"/> Charge any additional filing or application processing fees required under 37 CFR 1.16 and 1.17.					
Ronald P. Kanapen Attorney Reg. No.: 24,104 RADER, FISHMAN & GRAUER PLLC 1233 20th Street, N.W. Suite 501 Washington, DC 20036 (202) 955-3750				Dated: January 3, 2007	



Docket No.: SON-2920
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Hironori IBUSUKI

Application No.: 10/780,667

Confirmation No.: 1986

Filed: February 19, 2004

Art Unit: 1756

For: EXPOSURE PATTERN OR MASK AND
INSPECTION METHOD AND
MANUFACTURE METHOD FOR THE SAME

Examiner: Christopher G. Young

RESPONSE TO RESTRICTION REQUIREMENT

MS Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In full and timely response to the election of invention requirement of December 12, 2006,
please amend the above-identified application as follows:

Amendments to the claims begin at page 2 of this paper.

Remarks begin at page 5 of this paper.